



# **An Electro-Optic Voltage Measurement Device**

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## **Measuring High Voltage Pulses**

**August 2, 2007**

**NCSLI Annual Workshop and Symposium**

**St. Paul, Minnesota**

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under contract DE-AC04-94AL85000.





# **Pulsed Voltage Metrology Challenges**

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- **Bandwidth Limitations**
- **Electromagnetic interference**
- **Inability to use standard signal averaging techniques to lower noise bandwidth**



## **Promise of Electro-Optic Techniques**

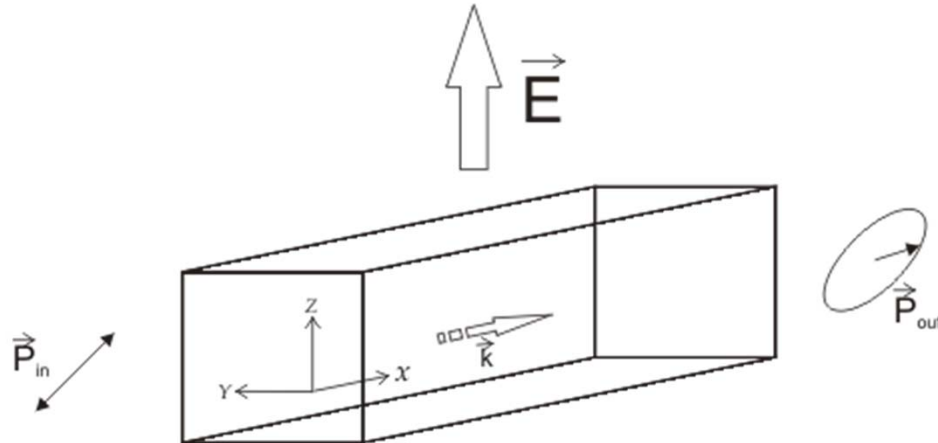
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- **Electro-optic voltage calibrator for pulsed high voltage: inherently high bandwidth and electrically isolated**
- **Expected uncertainty 0.5% (k=2)**
- **2kV-325kV, 2.5 $\mu$ sec - 25 $\mu$ sec pulse width**
- **Prototype device to be installed in PSL Pulsed High Voltage Measurement System**



# Optical E-Field Measurements

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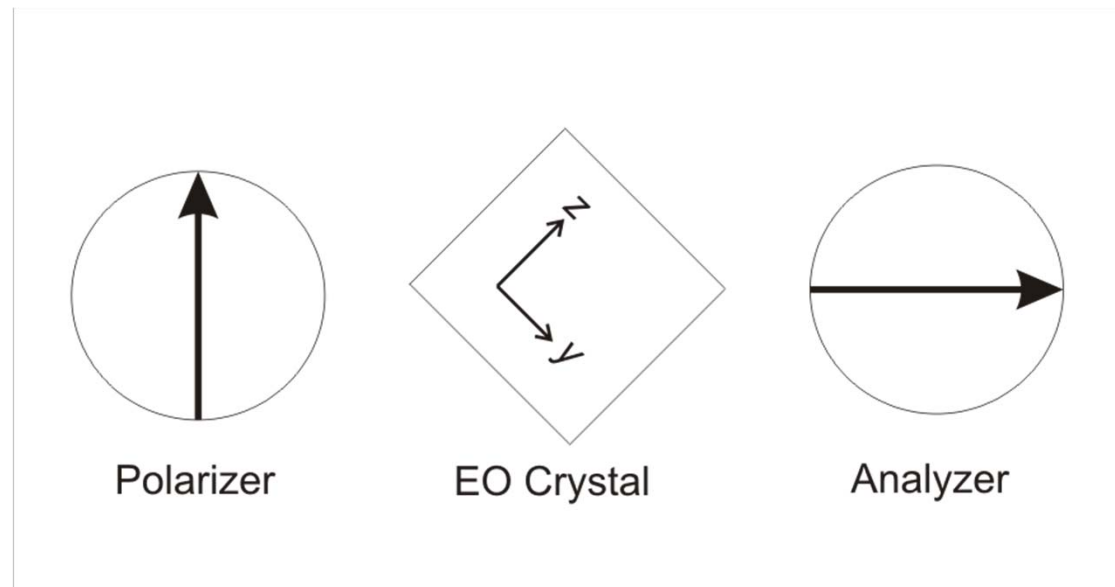
For LiNbO<sub>3</sub>:

$$\Gamma = \frac{\omega L}{2c} \left[ n_{oz}^3 r_{33} - n_{oy}^3 (r_{13} - r_{22}) \right] E_z$$



# Crystal Geometry

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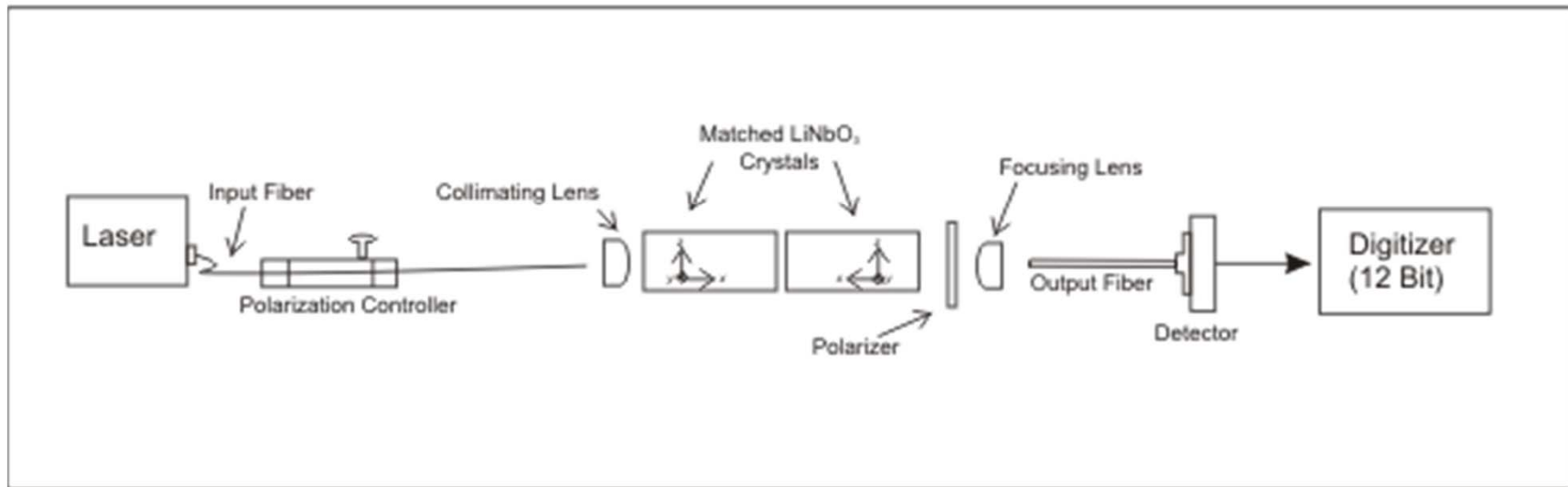


$$I_{out} = \frac{I_o}{2} [1 + \cos(\Gamma + \phi_{in})]$$



# Optical Configuration

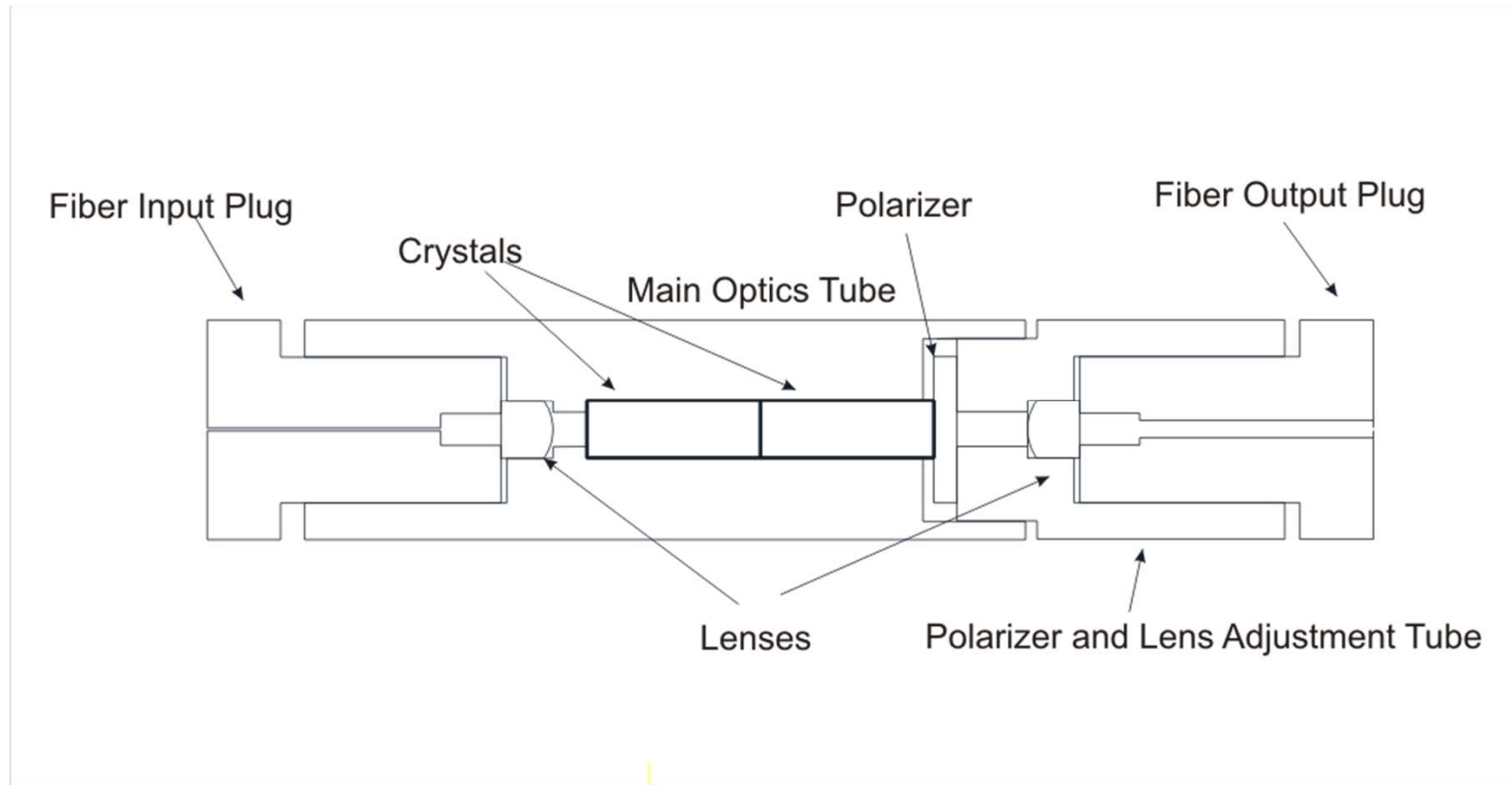
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# Opto-Mechanical Design

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# PHVMS at Sandia

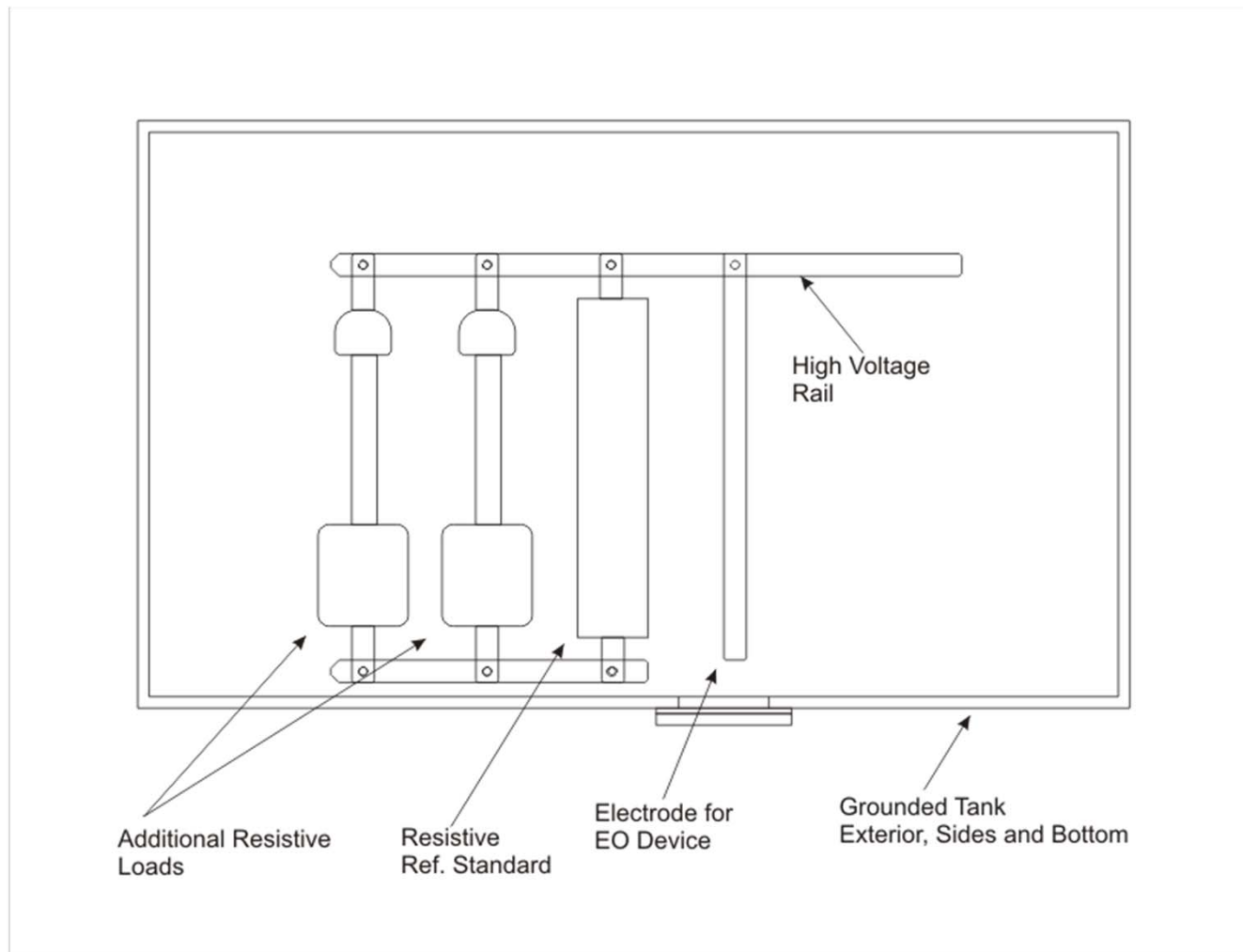
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# Installation in Tank





# Estimated Uncertainty Sources

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| Source               | Type A/B | Category    | Approx. Mag. | Impact           | Determination Method |
|----------------------|----------|-------------|--------------|------------------|----------------------|
| Laser Noise          | B        | Statistical | 0.0001*S     | Negligible       | Estimated            |
| Optical Scattering   | B        | Systematic  | 0.0001*S     | Negligible       | Estimated            |
| Detector Noise       | B        | Statistical | 6 mV         | Significant      | Manufacturers Specs. |
| Digitizer Noise      | B        | Statistical | 0.05-0.2%FS  | Significant      | Manufacturers Specs. |
| Digitizer Accuracy   | B        | Systematic  | 0.15%FS      | Most Significant | Manufacturers Specs. |
| Digitizer Resolution | B        | Systematic  | 0.025%FS     | Negligible       | Manufacturers Specs. |



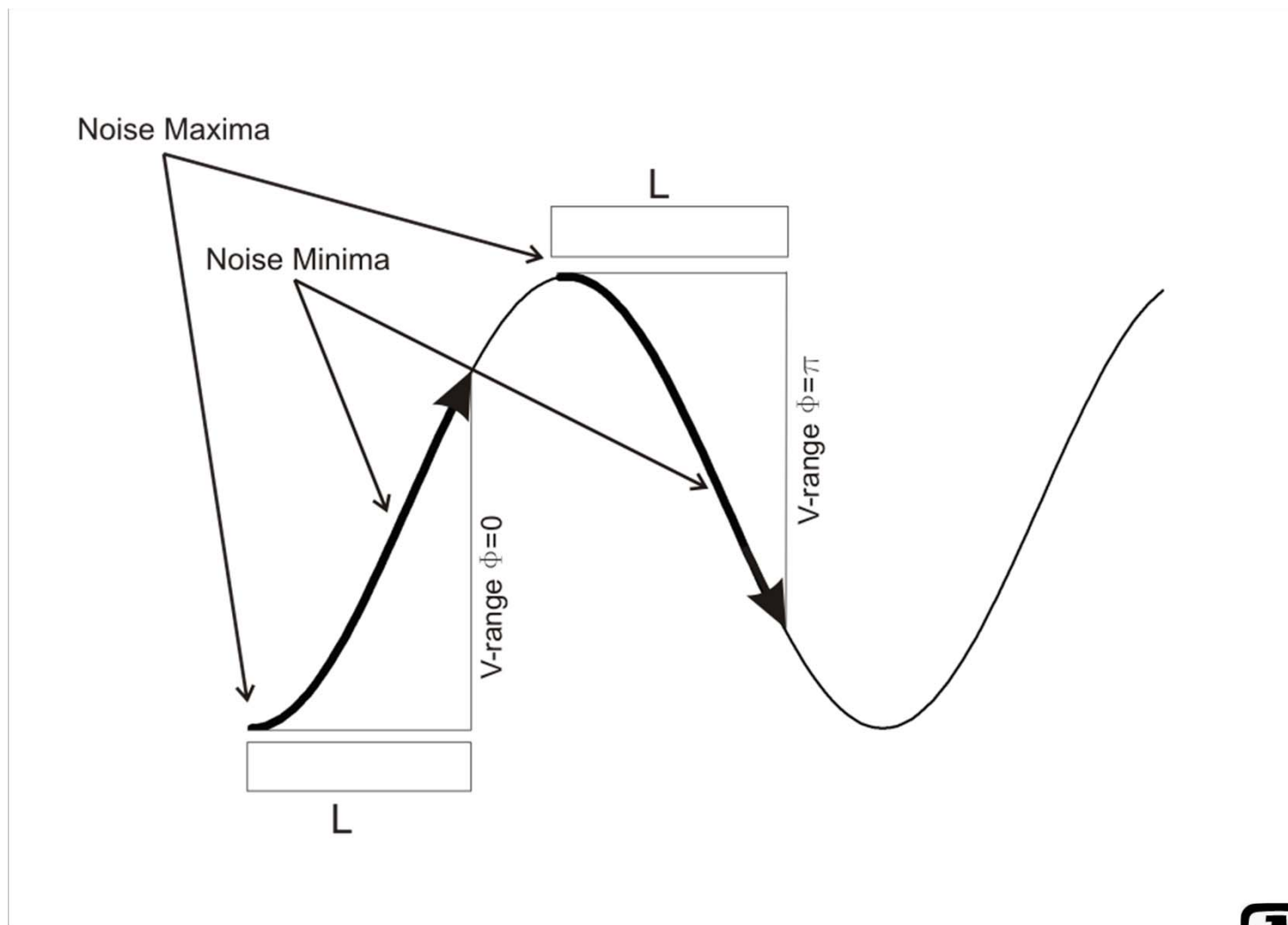
## Expected Expanded Uncertainty

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| Impressed Pulsed Voltage | Induced Phase Mod (degrees, Bias=0) | Unc. (k=2)<br>L=15mm, Bias=0,<br>P=2mW |
|--------------------------|-------------------------------------|--|
| 1.00E+04                 | 3                                   | 3.00                                   |
| 2.00E+04                 | 7                                   | 0.89                                   |
| 3.00E+04                 | 10                                  | 0.52                                   |
| 5.00E+04                 | 17                                  | 0.27                                   |
| 7.50E+04                 | 26                                  | 0.19                                   |
| 1.00E+05                 | 34                                  | 0.23                                   |
| 1.50E+05                 | 51                                  | 0.21                                   |
| 2.00E+05                 | 68                                  | 0.13                                   |
| 3.00E+05                 | 102                                 | 0.16                                   |
| 3.50E+05                 | 119                                 | 0.37                                   |



# Adjustable Parameters





## Summary

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- **In-situ electro-optic calibration device for pulsed high voltages is underway at SNL PSL.**
- **Expected to improve uncertainty ( $<0.5\%$ ) and has potential for high bandwidth measurements**